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2 Electroluminescence of silicon nanocrystals in p–i–n diode structures

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9 Abstract

10 A new method of fabrication of nanocrystalline silicon-based light-emitting-devices is introduced. Si nanocrystals are derived from combustion
11 or pyrolysis of silane and etched subsequently in a two-phase solution of HF. The p–i–n diodes have an active layer (20–60 nm) of Si
12 nanocrystals sandwiched between thin isolating layers of SiO₂ or a-Si:H and a top-layer of p⁺ doped silicon, the substrate being of n⁺ Si. For both
13 types of structures, electroluminescence is observed under forward bias exceeding 5 V and the spectrum consists of a broad band (due to a large
14 size distribution of Si nanocrystals) centred around 650 nm and giving a yellowish appearance when observed by naked-eye. The integrated
15 electroluminescence intensity grows with the square of applied bias.

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21 1. Introduction

22 Current research on silicon nanostructures is partly moti-
23 vated by the potential fabrication of Si-based light-emitting-
24 devices (LED) which are necessary for building up all-silicon
25 optoelectronics. Many different LED systems containing Si
26 nanocrystals (Si-NCs) were prepared and investigated: mainly
27 the electrochemical etching of p–n junctions in Si wafer [1]
28 and the Si-ion implantation of thin SiO₂ slabs in p–i–n
29 structures [2]. The external quantum efficiency has reached
30 about 1% [3] but the stability seems to be inversely
31 proportional to quantum efficiency and has been preventing
32 (up to now) application of Si-based LEDs in commercial
33 devices. The photoluminescence (PL) of Si-NCs is, in
34 principle, very efficient, quantum efficiency exceeding 80%
35 was reported for individual porous Si particles [4], but for
36 practical efficient EL structures a good injection of carriers into
37 Si-NCs must be achieved. This is difficult due to the presence
38 of a potential barrier which is, on the other hand, necessary for
39 confinement of electrons and holes inside the nanocrystal and

improvement of radiative recombination probability (shielding 40
from nearby defects and increased oscillator strength). Differ- 41
ent approaches are explored to achieve good injection into Si- 42
NCs, for example the recent use of MOSFET transistor 43
structure containing Si-NCs in the gate oxide [5]. 44

In this work we introduce a new approach to prepare silicon 45
nanocrystalline LEDs. Si-NCs, formed by combustion of silane 46
and etching by HF [6], are placed in the p–i–n silicon 47
structures, which show visible quasi-white EL under DC 48
forward bias of 5 to 10 V. Here we present measurements of 49
their electrical and optical properties. 50

2. Sample preparation and electrical characterization 51

Silicon nanocrystals are fabricated by a two step process. 52
First, large Si nanoparticles (several tens of nm) coated by an 53
oxide layer are grown by the combustion of silane (SiH₄) (i.e. 54
by burning of silane in air highly diluted with argon as 55
described previously [6] or by pyrolysis of 5% SiH₄ in H₂ 56
heated to 1100 °C in a quartz tube). In order to activate visible 57
PL of Si-NCs the nanoparticle size is reduced by etching with 58
hydrofluoric acid in the two-phase cyclohexane/propanol-2 59
solution. The PL peak is shifting from 850 nm down to about 60
640 nm with decreasing size of Si-NCs (see Fig. 3B, curve c). 61

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The mechanism of PL in Si-NCs is related to the size quantization and surface state effects [7,8].

Various LED structures containing Si-NCs were prepared. Here we present two of them (see Fig. 1).

Type A: a thin layer (of about 20–60 nm) of the Si-NC (diameter of ~2–3 nm) is deposited (by dropping of suspension on the wafer) on a Si wafer (n^+) covered by a thin layer (50 nm) of n^+ -doped amorphous hydrogenated silicon (a-Si:H) and a thick layer (350 nm) of undoped a-Si:H. Then the structure is covered by another layer (100 nm) of undoped a-Si:H, a 50 nm layer of p^+ -doped a-Si:H, and finally a 250 nm-thick indium–tin-oxide circular contact (1 mm diameter).

Type B: a crystalline Si wafer (n^+) covered by 10 nm layer of SiO_2 (by chemical vapour deposition) is covered electrochemically by about 50 nm-thick layer of Si-NCs by immersing it to a colloidal suspension of Si-NCs and biasing it negatively. Then another layer of SiO_2 (10 nm), p^+ -doped a-Si:H layer (50 nm), and a 250 nm-thick indium–tin-oxide contact are deposited on top of the structure.

The p – i – n LED structures of Type A reveal a high rectification factor of about 10^4 – 10^5 , while the Type B has rectification factor of about 10 (see Fig. 2).

3. Electroluminescence characteristics

EL images and spectra are studied by a microscope imaging system connected to an imaging spectrograph (Jobin-Yvon Triax 320) with an intensified CCD camera (Princeton Instruments PI-MAX). The PL spectrum of Si-NCs colloidal suspension was obtained using fluorescence spectrometer Spex Fluoromax-3.

The EL signal is proportional to passing current and becomes detectable under forward bias higher than about 5 V. EL images reveal important inhomogeneity of the LED emission. Only a part of the contact area is emitting detectable EL (about 10% in best case). For bias of about 10 V the EL emission may be observed by naked-eye as white light. EL

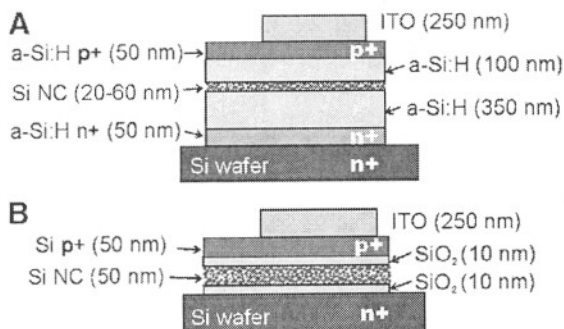


Fig. 1. Schematics of the LED structures: (A) the p – i – n structure with Si-NCs embedded between a-Si:H layers, (B) the p – i – n structure with Si-NCs sandwiched between thin SiO_2 layers.

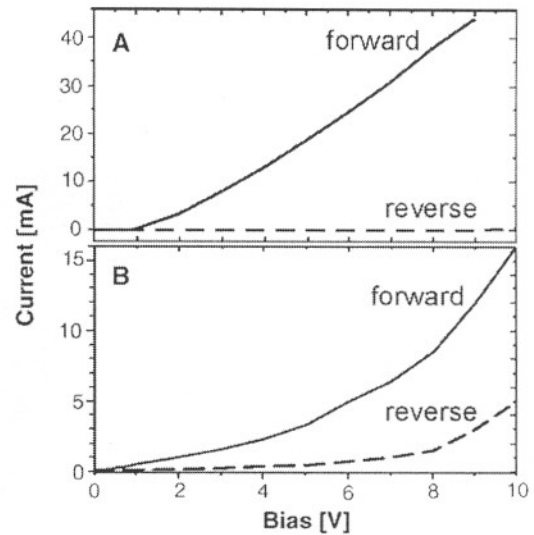


Fig. 2. Current–voltage (DC) characteristics of the two types of diodes, the solid and dashed curves indicate forward and reverse bias, respectively. (Forward polarity corresponds to negative voltage applied to the n^+ Si wafer.)

spectra are broad, covering almost the whole visible range and peaked around 660 nm (Fig. 3A, curve a). When taking into account absorbance of the top LED layers (Fig. 3A, curve c) we found the peak of internal EL spectrum is blue-shifted to about 650 nm, which is comparable to PL spectra of free Si-NCs (Fig. 3B, curve c). In Fig. 3B we compare the EL spectra

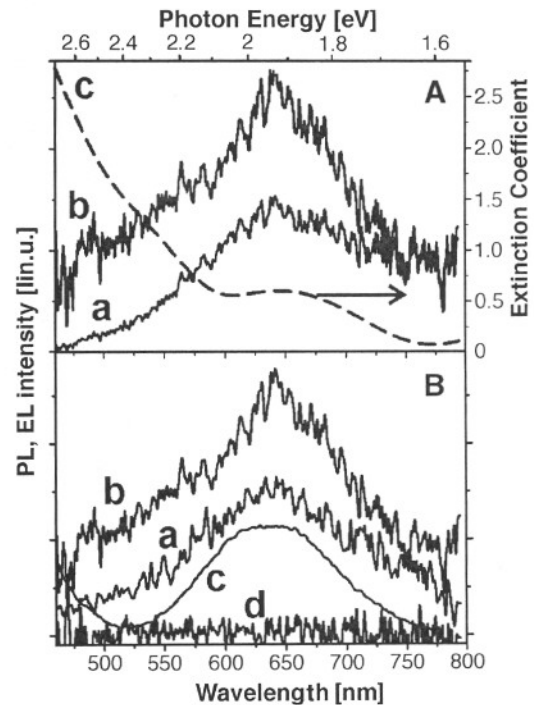


Fig. 3. The EL spectrum of the LED of Type B under forward bias of 10 V: (a) as measured, (b) corrected for reabsorption due to the top layers, (c) extinction coefficient of the diode layers above the Si-NCs layer. Comparison of the corrected EL spectra of LED Type A and B (curves (a) and (b), respectively) and PL spectra of the original Si-NCs in the colloidal suspension ($\lambda_{\text{exc}} = 400$ nm, curve (c)). The curve (d) illustrates the EL from a LED structure containing no Si-NCs.

Panel A:

Panel B:

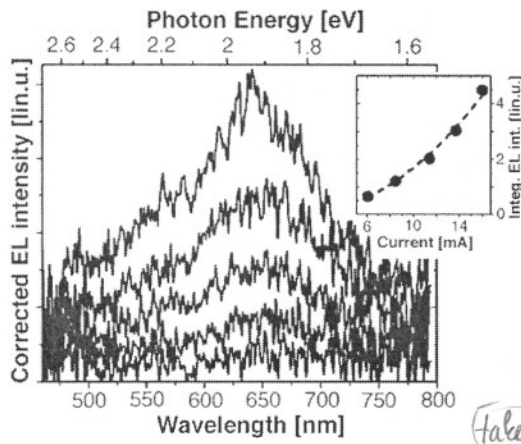


Fig. 4. Evolution of the EL spectra with increasing forward bias (7, 8, 9, 9.5, and 10 V, from bottom up). The spectra are corrected for the absorption losses in the upper diode layers. Integrated EL signal vs. current is shown in the inset. The line is a fit by function $I_{EL} = \text{const} \times C^2$.

159 of sample of Type A and B (curves a and b) with the PL
160 spectrum of the original Si-NCs colloidal suspension
161 ($\lambda_{exc} = 400$ nm) and also a “blank” sample of Type B containing
162 no Si-NCs (curve d).

163 Evolution of the EL spectra of sample Type B with
164 increasing bias is plotted in Fig. 4. The plot of integrated EL
165 intensity vs. current (see inset in Fig. 4) shows approximately
166 quadratic dependence.

167 4. Discussion and conclusions

168 We presented a new method on how to prepare nanocrystal-
169 line silicon-based LED in the visible region. The method
170 employs nanocrystals, derived from combustion or pyrolysis of
171 silane and etched subsequently in a two-phase solution of HF.
203

172 Good coincidence of the EL spectra in two different types of
173 sandwich structures with the PL emission spectrum of naked
174 Si-NCs strongly indicates that the origin of EL lies in the
175 ensemble of the Si-NCs. The emission spectra are quite broad,
176 obviously due to large Si-NCs size distribution. The observed
177 quadratic dependence of EL intensity upon the forward current
178 may indicate, according to Kanemitsu [9], a bimolecular
179 recombination mechanism, i.e. direct injection of both elec-
180 trons and holes into the Si-NCs. However, more firm
181 conclusions can be made when completing further investiga-
182 tions, including application of a pulsed current excitation, the
183 determination of external quantum efficiency and of a long-
184 term stability.

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